

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Previously Presented) A plasma treatment apparatus comprising:
a plasma generation unit comprising a first electrode and a plurality of second electrodes opposed to the first electrode;
a gas supply unit for blowing a process gas into a space between the first electrode and the plurality of second electrodes; and
a unit for selectively applying a voltage to at least one electrode among the plurality of second electrodes,
wherein the plurality of second electrodes are arranged linearly in one line or a plurality of lines.

2. (Currently Amended) A plasma treatment apparatus comprising:
a plasma generation unit comprising a first electrode and a plurality of second electrodes opposed to the first electrode;
a gas supply unit for blowing a process gas into a space between the first electrode and the plurality of second electrodes; and
a unit for selectively applying a voltage to at least one electrode among the plurality of second electrodes,
wherein the plurality of second electrodes ~~plasma-generation units~~ are arranged linearly in one line or a plurality of lines; and
wherein at least one of the plurality of second electrodes has a length of equal to or less than 1 mm on a side of an object to be treated.

3. (Currently Amended) A plasma treatment apparatus comprising:
a plasma generation unit comprising a first electrode and a plurality of second electrodes opposed to the first electrode for forming a pattern on an object to be treated;

a gas supply unit for blowing a process gas into a space between the first electrode and the plurality of second electrodes; and

a unit for selectively applying a voltage to at least one electrode among the plurality of second electrodes,

wherein the plurality of second electrodes ~~plasma generation units~~ are arranged linearly in one line or a plurality of lines; and

wherein at least one of the plurality of second electrodes has a length of equal to or less than a square of a line width of the pattern on a side of the object to be treated.

4. (Original) A plasma treatment apparatus according to claim 3, wherein the pattern is a wiring pattern.

5. (Previously Presented) A plasma treatment apparatus according to claim 2 further comprising a unit for positioning one of the plurality of plasma generation units to the object to be treated.

6. (Previously Presented) A plasma treatment apparatus according to claim 3 further comprising a unit for positioning one of the plurality of plasma generation units to the pattern on the object to be treated.

7. (Previously Presented) A plasma treatment apparatus according to claim 1, wherein a relatively scanning of the plurality of plasma generation units is synchronized with the application of the voltage to the predetermined electrode.

8. (Previously Presented) A plasma treatment apparatus according to claim 2, wherein a relatively scanning of the plurality of plasma generation units is synchronized with the application of the voltage to the predetermined electrode.

9. (Previously Presented) A plasma treatment apparatus according to claim 3, wherein a

relatively scanning of the plurality of plasma generation units is synchronized with the application of the voltage to the predetermined electrode.

10. (Previously Presented) A plasma treatment apparatus according to claim 1, wherein the plurality of second electrodes are processed by using a focused ion beam apparatus, photolithography, or a laser lithography apparatus.

11. (Previously Presented) A plasma treatment apparatus according to claim 2, wherein the plurality of second electrodes are processed by using a focused ion beam apparatus, photolithography, or a laser lithography apparatus.

12. (Previously Presented) A plasma treatment apparatus according to claim 3, wherein the plurality of second electrodes are processed by using a focused ion beam apparatus, photolithography, or a laser lithography apparatus.

13. (Previously Presented) A plasma treatment apparatus according to claim 1, wherein the first electrode and the plurality of second electrodes are covered with a dielectric.

14. (Previously Presented) A plasma treatment apparatus according to claim 2, wherein the first electrode and the plurality of second electrodes are covered with a dielectric.

15. (Previously Presented) A plasma treatment apparatus according to claim 3, wherein the first electrode and the plurality of second electrodes are covered with a dielectric.

16. (Previously Presented) A plasma treatment apparatus according to claim 1, wherein the voltage is applied to the predetermined electrode for performing a film formation, an etching treatment, or a surface modification over an object to be treated.

17. (Previously Presented) A plasma treatment apparatus according to claim 2, wherein

the voltage is applied to the predetermined electrode for performing a film formation, an etching treatment, or a surface modification over an object to be treated.

18. (Previously Presented) A plasma treatment apparatus according to claim 3, wherein the forming of the pattern is performed under atmospheric pressure or under pressure approximate to atmospheric pressure.

19. (Previously Presented) A plasma treatment apparatus according to claim 1 further comprising a stage to which an object to be treated is fixed,
wherein a scanning of the stage is synchronized with the application of the voltage to the predetermined electrode.

20. (Previously Presented) A plasma treatment apparatus according to claim 2 further comprising a stage to which the object is fixed,
wherein a scanning of the stage is synchronized with the application of the voltage to the predetermined electrode.

21. (Previously Presented) A plasma treatment apparatus according to claim 3 further comprising a stage to which the object is fixed,
wherein a scanning of the stage is synchronized with the application of the voltage to the predetermined electrode.

22. (Previously Presented) A plasma treatment apparatus according to claim 16, wherein the film formation, the etching treatment, or the surface modification is performed under atmospheric pressure or under pressure approximate to atmospheric pressure.

23. (Previously Presented) A plasma treatment apparatus according to claim 17, wherein the film formation, the etching treatment, or the surface modification is performed under atmospheric pressure or under pressure approximate to atmospheric pressure.

24. (Previously Presented) A plasma treatment apparatus comprising:
a plurality of plasma generation units each comprising a first electrode and a plurality of second electrodes;
a gas supply unit for blowing a process gas into a space between the first electrode and the plurality of second electrodes ; and
a unit for selectively applying a voltage to at least one electrode among the plurality of second electrodes,
wherein the plurality of plasma generation units are arranged linearly in one line or a plurality of lines.

25. (Previously Presented) A plasma treatment apparatus according to claim 24,
wherein a relatively scanning of the plurality of plasma generation units is synchronized with the application of the voltage to the predetermined electrode.

26. (Previously Presented) A plasma treatment apparatus according to claim 24, wherein the plurality of second electrodes are processed by using a focused ion beam apparatus, photolithography, or a laser lithography apparatus.

27. (Previously Presented) A plasma treatment apparatus according to claim 24, wherein the first electrode and the plurality of second electrodes are covered with a dielectric.

28. (Previously Presented) A plasma treatment apparatus according to claim 24, wherein the voltage is applied to the predetermined electrode for performing a film formation, an etching treatment , or a surface modification over an object to be treated.

29. (Previously Presented) A plasma treatment apparatus according to claim 24 further comprising a stage to which an object to be treated is fixed,
wherein a scanning of the stage is synchronized with the application of he voltage to the

predetermined electrode.

30. (Previously Presented) A plasma treatment apparatus according to claim 28, wherein the film formation, the etching treatment, or the surface modification is performed under atmospheric pressure or under pressure approximate to atmospheric pressure.

31. (Previously Presented) A plasma treatment apparatus comprising:
a plasma generation unit comprising a first electrode and a plurality of second electrodes opposed to the first electrode;

a gas supply unit for blowing a process gas to a substrate to be treated through a space between the first electrode and the plurality of second electrodes ; and

a unit for selectively applying a voltage to at least one electrode among the plurality of second electrodes,

wherein the plurality of second electrodes are arranged linearly in one line or a plurality of lines.

32. (Previously Presented) A plasma treatment apparatus according to claim 31,
wherein a relatively scanning of the plurality of plasma generation units is synchronized with the application of the voltage to the predetermined electrode.

33. (Previously Presented) A plasma treatment apparatus according to claim 31, wherein the plurality of second electrodes are processed by using a focused ion beam apparatus, photolithography, or a laser lithography apparatus.

34. (Previously Presented) A plasma treatment apparatus according to claim 31, wherein the first electrode and the plurality of second electrodes are covered with a dielectric.

35. (Previously Presented) A plasma treatment apparatus according to claim 31, wherein the voltage is applied to the predetermined electrode for performing a film formation, an etching

treatment, or a surface modification over an object to be treated.

36. (Previously Presented) A plasma treatment apparatus according to claim 31 further comprising a stage to which an object to be treated is fixed,

wherein a scanning of the stage is synchronized with the application of the voltage to the predetermined electrode.

37. (Previously Presented) A plasma treatment apparatus according to claim 35, wherein the film formation, the etching treatment, or the surface modification is performed under atmospheric pressure or under pressure approximate to atmospheric pressure.